

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L9	8	(local near flare).clm.	US-PGPUB	OR	ON	2009/05/19 15:33

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L6	132	703/6.ccis. and @pd>="20081101"	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2009/05/19 14:39
L7	68	(local near flare)	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2009/05/19 15:05

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S16	1953	716/19.ccls.	US-PGPUB; USPAT; EPO; DERWENT	OR	ON	2009/05/19 15:57

The screenshot shows the Google Scholar search interface. At the top, there are links for Web, Images, Video, News, Maps, and more. Below that is a search bar containing the query "local flare". To the right of the search bar are date filters: "2000" and "2003", separated by a dash. A "Search" button is to the right of the date range. In the top right corner, there are three small buttons labeled "Ad", "Sc", and "Sc".

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Correction for local flare effects approximated with double Gaussian profile in ArF lithography

M Osawa, T Yao, H Aoyama, K Ogino, H Hoshino, Y ... - Journal of Vacuum Science & Technology B: Microelectronics ..., 2003 - link.aip.org

... been developed for correcting line width variations due to midrange flare with a scattering range of over a few tens of micrometers (which we call **local flare** ...

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Effectiveness and confirmation of local area flare measurement method in various pattern layouts

D Nam, E Lee, S Jung, YS Kang, G Yeo, J Lee, H Cho ... - Proceedings of SPIE, 2002 - link.aip.org

... The LOAFLER is designed to measure the local area flare of the lens, that is, the short and mid-range flare and the **local flare** distribution of the exposure ...

Cited by 5 - Related articles - Web Search - All 3 versions

Local flare effects and correction in ArF lithography

T Yao, M Osawa, T Minami, N Yamamoto, H Aoyama, G ... - VLSI Technology, 2003. Digest of Technical Papers, 2003 ..., 2003 - ieeexplore.ieee.org

Page 1. 4B-1 Local Flare Effects and Correction in ArF Lithography Teruyoshi Yao, Morimi Osawa, Takayoshi M ind , Norihiro Yamamoto, Hajime Aoyama, ...

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[PDF] ► Relevance of TCAD to process-aware design

V Singh, J Garcia-Colevatti - Proceedings of the SPIE, 2002 - leitl.org

... scattering, or flare. ô Flare and flare variation causes WID CD variation.

ô "Long range" layout variations affect **local flare**.

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Flare-induced CD variation correction using transmittance controlled mask

DS Nam, GS Yeo, JR Park, SW Choi, SG Woo, HK Cho, ... - Proceedings of SPIE, 2003 - link.aip.org

... In this paper, the **local flare** values are measured using dose-to-clear method and CD measurement method in order to confirm the exposure tool condition. ...

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7 Elm yellows in North America

WA Sinclair - The Elms: Breeding, Conservation, and Disease Management, 2000 - books.google.com

... in New York State, observed since 1971, has had the following characteristics (Lanier et al., 1988; Matteoni and Sinclair, 1988): • **local flare**-ups in ...

Cited by 7 - Related articles - Web Search - All 2 versions

Spectral Doppler and resistive index

L Terslev, S Torp-Pedersen, E Qvistgaard, H ... - Acta Radiologica, 2003 - informaworld.com

... Most often, the intra-articular injection is given as a supplement to systemic treatment of RA during a **local flare** up of the disease. ...

Cited by 11 - Related articles - Web Search - BL Direct - All 5 versions

Test photomask, flare evaluation method, and flare compensation method

T Yao, I Hanyu, K Kirikoshi - US Patent App. 10/400,399, 2003 - Google Patents

... in a zonal shape which becomes a flare causing pattern forming a light transmission region which surrounds the line pattern and causes **local flare** to occur on ...

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Nikon F2 exposure tool development

S Owa, Y Matsumoto, Y Ohmura, S Sakuma, T Aoki, J ... - Proceedings of SPIE, 2003 - link.aip.org

... We also report the measurement of refractive index inhomogeneity inside CaF₂ crystals, which is suspected as the cause of **local flare**. ...

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Analysis of imaging performance degradation

K Matsumoto, T Matsuyama, S Hirukawa - Proceedings of SPIE, 2003 - link.aip.org

... Higher frequency component beyond Zernike representation could cause a **local flare** that will be observed in the surrounding area of nominally bright patterns. ...

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Key authors: M Osawa - T Yao - H Aoyama - K Ogino - H Hoshino

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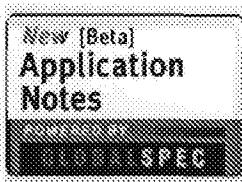
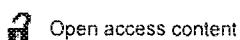

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Yao, T.; Osawa, M.; Minami, T.; Yamamoto, N.; Aoyama, H.; Okuda, G.; Saw Sugimoto, F.; Futatsuya, H.; Kobayashi, K.; Ogino, K.; Hoshino, H.; Machida, *VLSI Technology, 2003. Digest of Technical Papers. 2003 Symposium on* 10-12 June 2003 Page(s):43 - 44
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